

# S Santosh Kumar

## List of Publications by Year in descending order

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19  
papers

356  
citations

1307594

7  
h-index

1125743

13  
g-index

20  
all docs

20  
docs citations

20  
times ranked

288  
citing authors

#	ARTICLE	IF	CITATIONS
1	High-resolution current mode interface for MEMS piezoresistive pressure sensor. AEU - International Journal of Electronics and Communications, 2021, 134, 153707.	2.9	6
2	Development of a MEMS-based barometric pressure sensor for micro air vehicle (MAV) altitude measurement. Microsystem Technologies, 2020, 26, 901-912.	2.0	16
3	Modeling and FEM-Based Simulations of Composite Membrane Based Circular Capacitive Pressure Sensor. Lecture Notes in Electrical Engineering, 2020, , 497-506.	0.4	4
4	Mathematical Modelling and Comparative Study of Elliptical and Circular Capacitive Pressure Microsensor. Journal of Physics: Conference Series, 2019, 1240, 012068.	0.4	6
5	CMOS Compatible Wet Bulk Micromachining for MEMS Applications. , 2019, , .		0
6	Sensitivity and Linearity Enhancement of Piezoresistive Pressure Sensor Using Stress Concentration Structure. , 2019, , .		0
7	CCII Based Current Signal Interface for Piezoresistive Pressure Sensor. , 2018, , .		4
8	A MATLAB program for quick estimation of characteristics of piezoresistive pressure sensors. AIP Conference Proceedings, 2018, , .	0.4	1
9	Realization of MEMS-based silicon cantilever using bulk micromachining. , 2017, , .		0
10	Comparative study of characteristics of polysilicon pressure sensor with different diaphragm sizes and piezoresistor configurations. AIP Conference Proceedings, 2016, , .	0.4	1
11	Effect of piezoresistor configuration on output characteristics of piezoresistive pressure sensor: an experimental study. Microsystem Technologies, 2016, 22, 709-719.	2.0	24
12	Experimental evaluation of sensitivity and non-linearity in polysilicon piezoresistive pressure sensors with different diaphragm sizes. Microsystem Technologies, 2016, 22, 83-91.	2.0	30
13	Fabrication and characterization of pressure sensor, and enhancement of output characteristics by modification of operating pressure range. , 2015, , .		1
14	Polysilicon thin film piezoresistive pressure microsensor: design, fabrication and characterization. Microsystem Technologies, 2015, 21, 1949-1958.	2.0	45
15	Dynamic characterization of bulk micromachined accelerometer using laser doppler vibrometer (LDV). Microsystem Technologies, 2015, 21, 2221-2232.	2.0	7
16	Sensitivity and non-linearity study and performance enhancement in bossed diaphragm piezoresistive pressure sensor. , 2015, , .		11
17	Design principles and considerations for the "ideal"™ silicon piezoresistive pressure sensor: a focused review. Microsystem Technologies, 2014, 20, 1213-1247.	2.0	172
18	Design and Simulation of Bulk Micromachined Accelerometer for Avionics Application. Communications in Computer and Information Science, 2013, , 94-99.	0.5	5

#	ARTICLE	IF	CITATIONS
19	Analytical Modelling and FEM Simulation of Capacitive Pressure Sensor for Intraocular Pressure Sensing. IOP Conference Series: Materials Science and Engineering, 0, 404, 012026.	0.6	10